

In the Claims:

Please cancel claims 1-22. Please add new claims 23-41. The claims are as follows.

1-22. (Canceled)

23. (New) An electrical structure, comprising:

a semiconductor substrate having an electrically insulative isolation structure therein,
wherein a top surface of the substrate and a top surface of the insulation structure are coplanar;

a first gate oxide layer on the substrate and in direct mechanical contact with the top
surface of the substrate;

a first polysilicon layer on the first gate oxide layer and in direct mechanical contact with
the first gate oxide layer;

a second gate oxide layer on the isolation structure and in direct mechanical contact with
the top surface of the isolation structure, wherein the first and second gate oxide layers have a
same thickness in a first direction perpendicular to the top surface of the substrate, and wherein
the first gate oxide layer layer has a smaller width than the second gate oxide layer in a second
direction parallel to the top surface of the substrate; and

a second polysilicon layer on the second gate oxide layer and in direct mechanical contact
with the second gate oxide layer, wherein the first polysilicon layer has a smaller thickness than
the second polysilicon layer in the first direction, and wherein the first polysilicon layer has a
smaller width than the second polysilicon layer in the second direction.

24. (New) The electrical structure of claim 23, further comprising a first dielectric film
surrounding and in direct mechanical contact with the the first gate oxide layer and the first

polysilicon layer and in direct mechanical contact with the top surface of the substrate, wherein a combined thickness of the first polysilicon layer and the first dielectric film in the first direction exceeds the thickness of the second polysilicon layer in the first direction, and wherein a combined width of the first polysilicon layer and the first dielectric film in the second direction exceeds the width of the second polysilicon layer in the second direction.

25. (New) The electrical structure of claim 24, further comprising a second dielectric film surrounding and in direct mechanical contact with the first dielectric film and in direct mechanical contact with the top surface of the substrate.

26. (New) The electrical structure of claim 25, further comprising a diffusion area in the substrate, wherein the top surface of the substrate and a top surface of the diffusion area are coplanar, and wherein the top surface of the diffusion area is in direct mechanical contact with the first gate oxide layer, the first dielectric film, and the second dielectric film.

27. (New) The electrical structure of claim 24, wherein the first dielectric film comprises silicon oxide.

28. (New) The electrical structure of claim 24, wherein the first dielectric film comprises silicon nitride.

29. (New) The electrical structure of claim 23, further comprising a dielectric cap layer on the

first polysilicon layer and in direct mechanical contact with a top surface of the first polysilicon layer, and wherein the top surface of the first polysilicon layer is about parallel to the top surface of the substrate.

30.(New) The electrical structure of claim 29, further comprising an electrically insulative spacer in direct mechanical contact with the first gate oxide layer, the first polysilicon layer, and a side surface of the dielectric cap layer, and wherein a portion of the side surface of the dielectric cap layer is not in mechanical contact with the spacer.

31. (New) The electrical structure of claim 30, further comprising a diffusion area in the substrate, wherein the top surface of the substrate and a top surface of the diffusion area are coplanar, and wherein the top surface of the diffusion area is in direct mechanical contact with the first gate oxide layer and the spacer.

32. (New) The electrical structure of claim 29, wherein the dielectric cap layer comprises silicon oxide.

33. (New) The electrical structure of claim 29, wherein the dielectric cap layer comprises silicon nitride.

34. (New) The electrical structure of claim 29, wherein the spacer comprises a silicon-rich material.

35. (New) The electrical structure of claim 34, wherein the silicon-rich material comprises silicon-rich silicon nitride.

36. (New) The electrical structure of claim 34, wherein the silicon-rich material comprises silicon-rich silicon oxynitride.

37. (New) The electrical structure of claim 23, wherein the substrate comprises single crystal silicon.

38. (New) The electrical structure of claim 23, wherein the thickness of the first gate oxide in the first direction is 3 to 5 nanometers.

39. (New) A structure, comprising:

- a semiconductor substrate;

- a first gate oxide layer on the substrate and in direct mechanical contact with the top surface of the substrate;

- a first polysilicon layer on the first gate oxide layer and in direct mechanical contact with the first gate oxide layer; and

- a laser beam directed toward the polysilicon layer and adapted to trim the first polysilicon layer by a film growth method that is selective to laser-absorbing polysilicon.

40. (New) The structure of claim 39, further comprising:

an electrically insulative isolation structure within the substrate, wherein a top surface of the substrate and a top surface of the insulation structure are coplanar;

a second gate oxide layer on the isolation structure and in direct mechanical contact with the top surface of the isolation structure; and

a second polysilicon layer on the second gate oxide layer and in direct mechanical contact with the second gate oxide layer, wherein the laser beam is not directed toward the second polysilicon layer and is not adapted to trim the second polysilicon layer.

41. (New) The structure of claim 39, wherein the film growth method comprises selective surface nitridation.